## PATENT ABSTRACTS OF JAPAN

(11)Publication number:

2002-124208

(43) Date of publication of application: 26.04.2002

(51)Int.CI.

H01J 49/10 G01N 27/62 H01J 49/04

(21)Application number: 2001-242091 (71)Applicant: ANELVA CORP

(22)Date of filing:

09.08.2001

(72)Inventor: SHIOKAWA YOSHIRO

**NAKAMURA MEGUMI** 

SASAKI TORU **FUJII TOSHIHIRO** 

(30)Priority

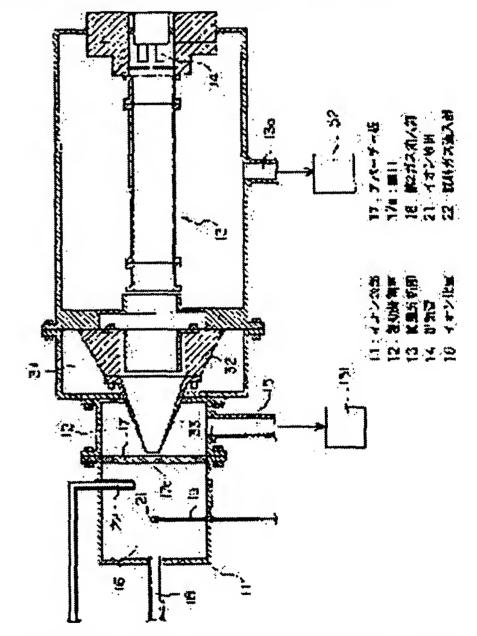
Priority number: 2000242473 Priority date: 10.08.2000 Priority country: JP

## (54) IONIZING METHOD FOR MASS SPECTROMETRY AND MASS SPECTROMETER

## (57)Abstract:

PROBLEM TO BE SOLVED: To provide an ionizing method for mass spectrometry and a mass spectrometer, suppressing the contact of a ample gas with a metal ion emitter, preventing the contamination of the metal ion emitter, and stably conducting the mass spectrometry for a long time.

SOLUTION: Metal ions are attached to the sample gas in an ionizing chamber 16 to produce sample gas ions, the sample gas ions are passed through a mass spectrometry part 13 formed with an electromagnetic field and masssegregated, and the mass-segregated sample gas ions are detected and measured as ion current with a detecting part 14. The metal ion emitter 21 emitting metal ions is arranged in the upstream position of a region controlled in the pressure reducing atmosphere where gas flow becomes viscouse flow, a sample gas



inflow part 2 introducing the sample gas is arranged in the downstream position where the metal ions are carried, and the ionized sample gas attached with the metal ions is carried to the mass spectrometry part through an opening 17a of an aperture plate 17.

## LEGAL STATUS

[Date of request for examination] [Date of sending the examiner's decision of rejection]

[Kind of final disposal of application other than the examiner's decision of rejection or application converted registration]
[Date of final disposal for application]
[Patent number]
[Date of registration]
[Number of appeal against examiner's decision of rejection]
[Date of requesting appeal against examiner's decision of rejection]
[Date of extinction of right]

Copyright (C); 1998,2003 Japan Patent Office